FIG.1 (PRIOR ART)

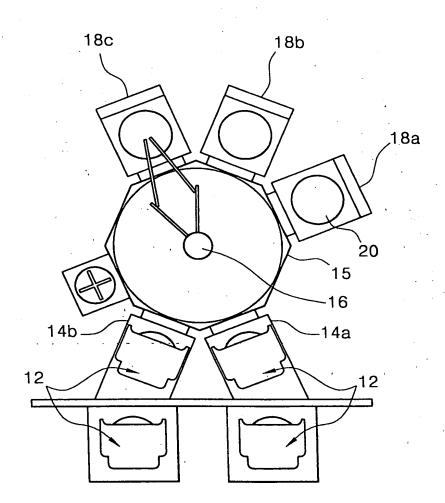
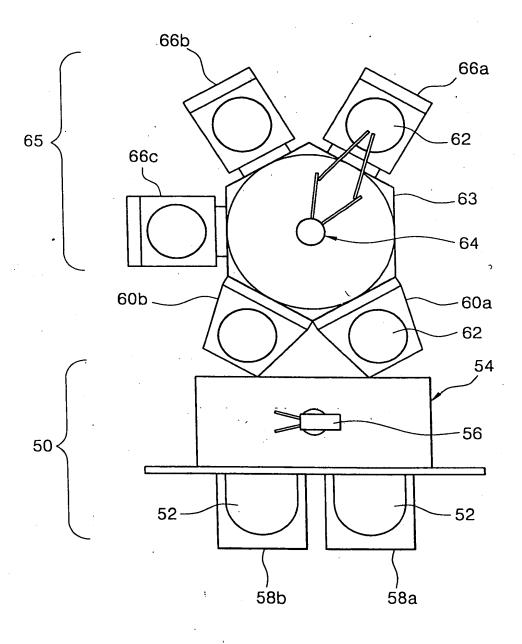
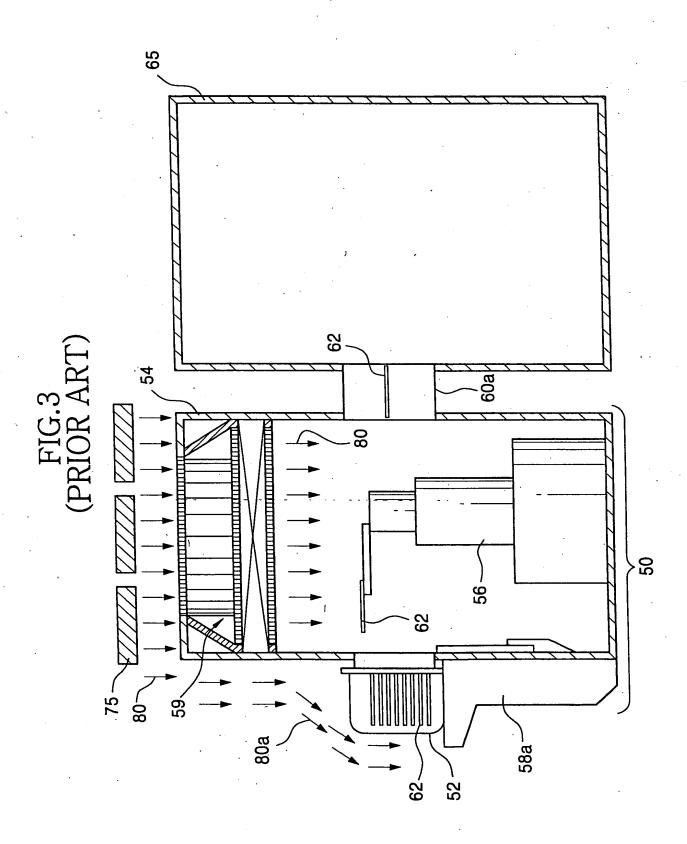


FIG.2 (PRIOR ART)





"Substrate Processing Apparatus And Method of Processing Substrate While Controlling For Contamination in Substrate Transfer Module"

Serial No. (New) - Attny. Doc. No. SEC.1087

Inventors: Yo-Han AHN et al.

FIG.4 (PRIOR ART)

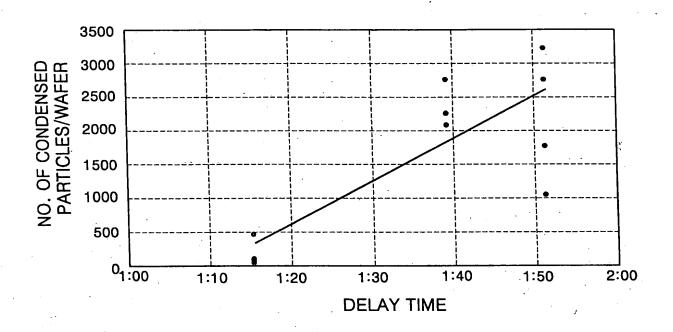


FIG.5

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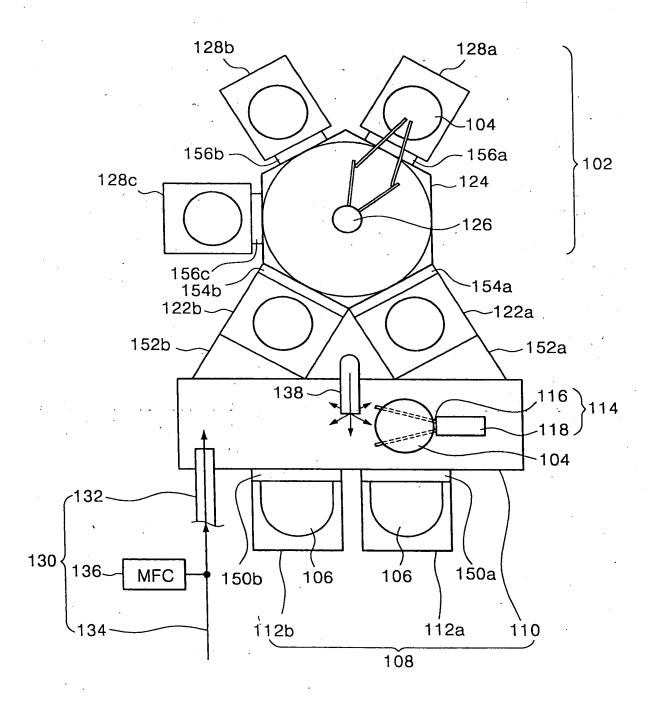
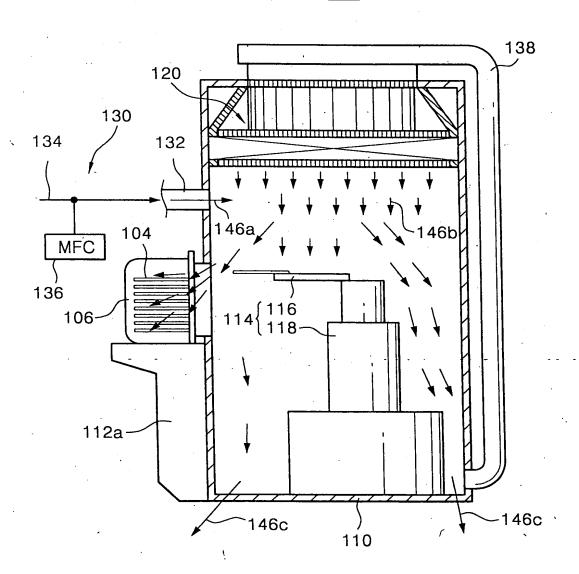
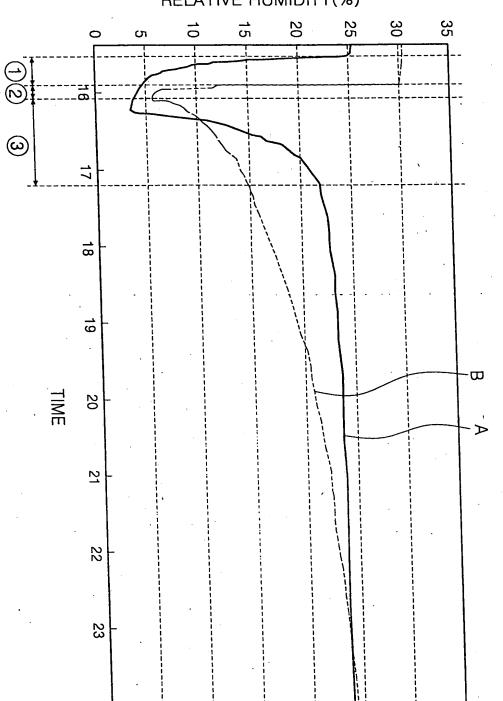


FIG.6

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ìG.7

FIG.8

